



**Integrated Power Conversion and Power Management**

*next generation technology for emerging business opportunities, October 17, 18, 19, 2018, Hsinchu, Taiwan*

*new technologies new applications new markets*

# Understanding the Dynamic Behavior in GaN-on-Si Power Devices and IC's

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# Outline

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- ❑ **Dynamic  $R_{ON}$  and beyond**
- ❑ **Other important dynamic behavior**
  - **Dynamic  $V_{TH}$**
  - **Dynamic  $I_{OFF}$**
- ❑ **Integrated gate driver for enhanced reliability**
  - **Rail-to-rail output**
  - **Suppressed gate ringing and false turn-on**
- ❑ **Summary**

# Commercial GaN-on-Si power devices

## COMPARISON OF KEY FIGURES-OF-MERIT

Device	Rating [V]	$R_{\text{DS(on)}}$ [m $\Omega$ ]	$R_{\text{DS(on)}} \cdot Q_{\text{OSS}}$ [m $\Omega \cdot \mu\text{C}$ ]	$R_{\text{DS(on)}} \cdot Q_{\text{RR}}$ [m $\Omega \cdot \mu\text{C}$ ]	$R_{\text{DS(on)}} \cdot E_{\text{OSS}}$ [m $\Omega \cdot \mu\text{J}$ ]	$R_{\text{DS(on)}} \cdot Q_{\text{G}}$ [m $\Omega \cdot \text{nC}$ ]	$V_{\text{GS\_max}}$ [V]
Si SJ	600	56	23.5	336.0	450	3800	20
GaN E-mode GIT	600	55	2.2	2.2	350	300	N.A.
GaN E-mode	650	50	2.8	2.8	350	290	7
GaN Cascode	650	52	5	7.0	730	1460	18
SiC DMOS	900	65	4.5	8.5	570	1950	18
SiC TMOS	650	60	3.8	3.3	540	3480	22

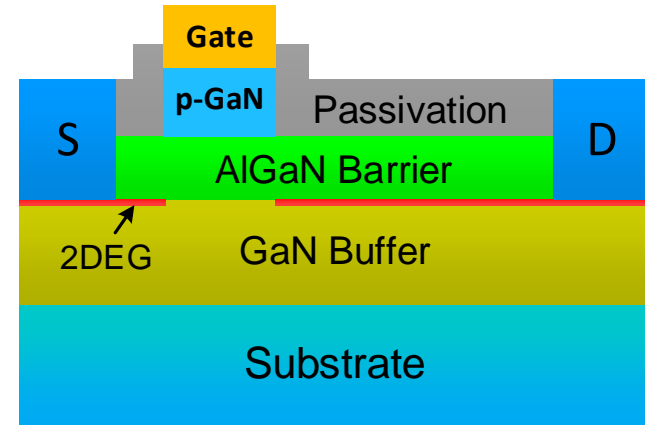
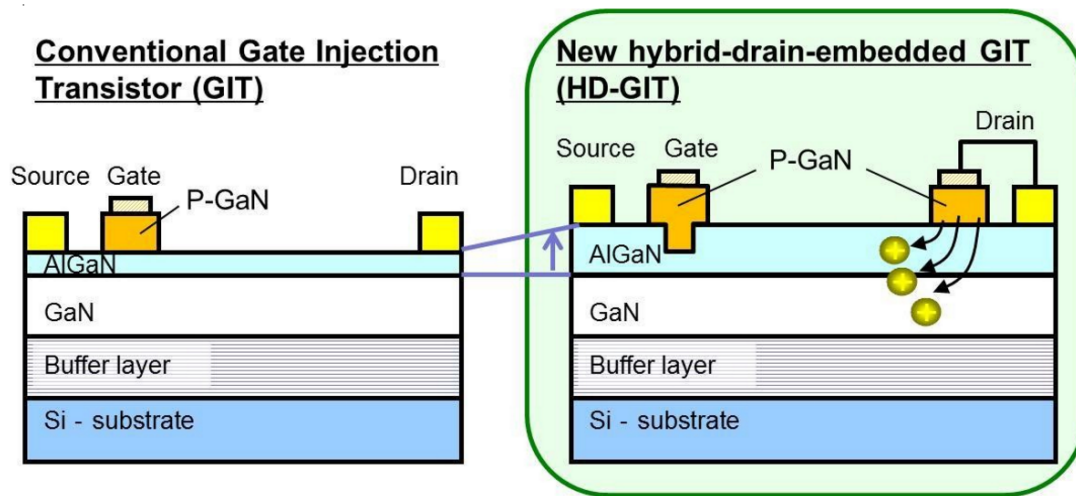
\* GIT is a **current driven** device typically used with an RC network and a standard gate driver.

*K. J. Chen, O. Häberlen, A. Lidow, C.-L. Tsai, T. Ueda, Y. Uemoto and Y. Wu, "GaN-on-Si Power Technology: Devices and Applications," IEEE Trans. Electron Devices, vol. 64, p. 779, 2017.*

# Commercial E-mode $\rho$ -GaN HEMTs

Type I: ohmic-type gate

Type II: Schottky-type gate



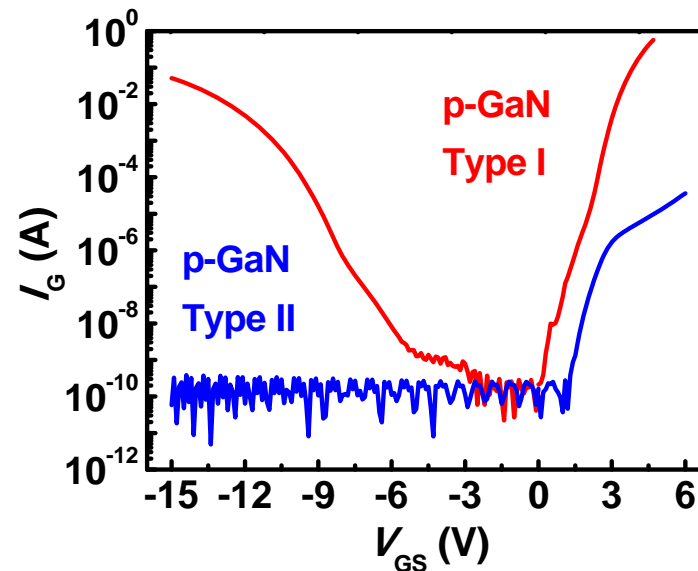
Voltage-driving

Panasonic

Current-driving

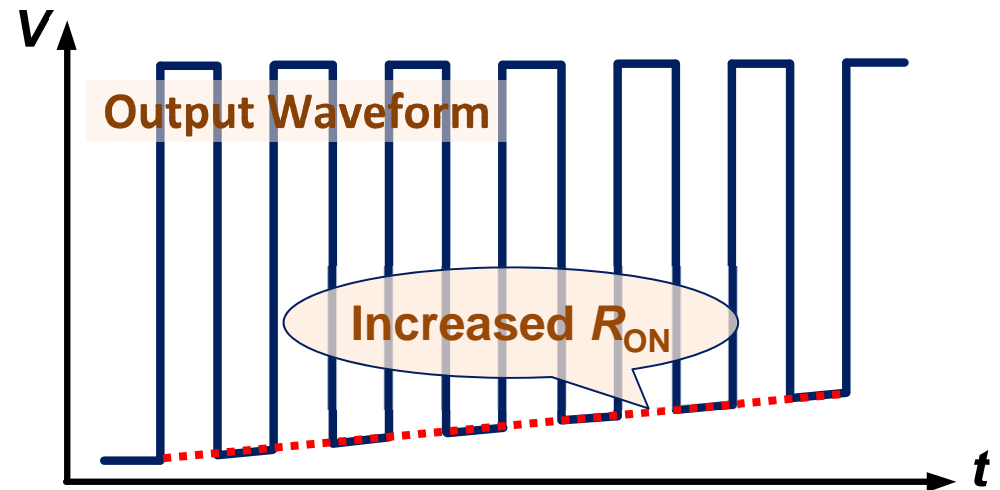
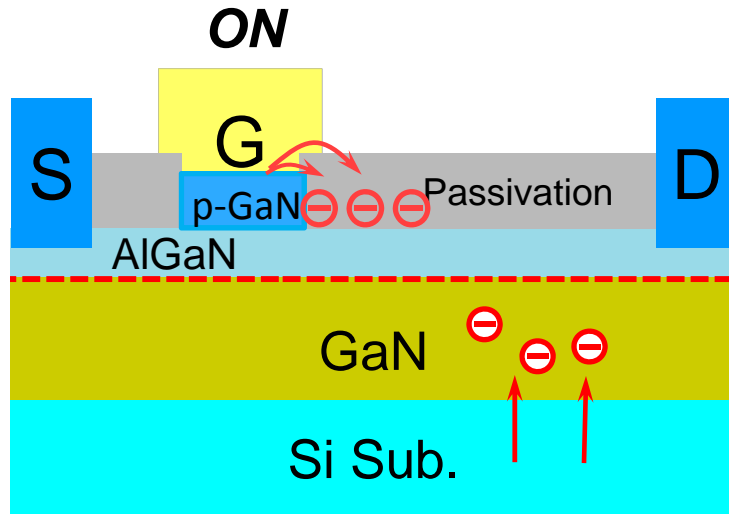
## Different gate contact

- Different gate driving schemes
- Different dynamic  $V_{TH}$  behavior



# Dynamic behavior in GaN power devices

**Dynamic  $R_{ON}$  has been the major focus.**

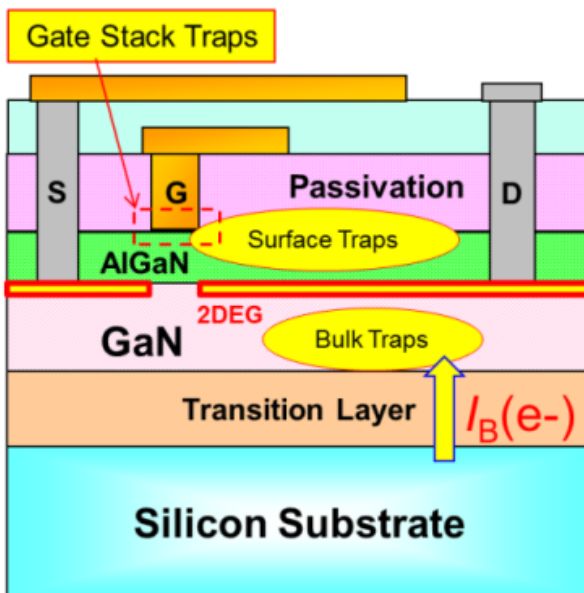


- Electron trapping at the OFF state (at large  $V_D$ )
  - Interface traps
  - buffer traps
- Reduced carrier density
- Dynamic  $R_{ON}$  degradation
- Increased  $V_{ON}$

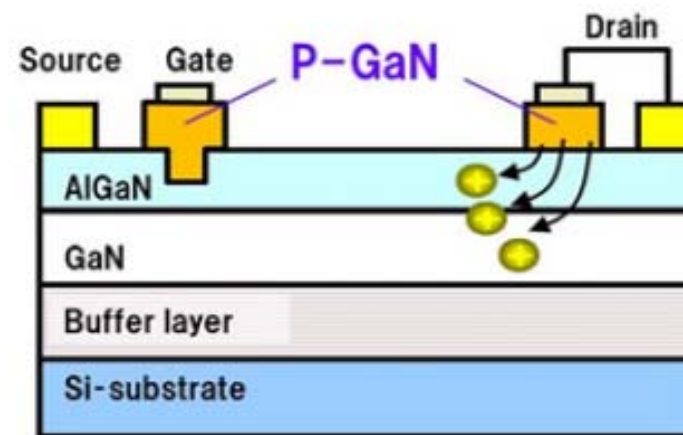
**Increased conduction loss and lower efficiency!**

# Suppression of dynamic $R_{ON}$ degradation

- Passivation technology + field plate
- Hole injection for trap compensation
- Buffer optimization (carbon doping profile, “leaky buffer”, etc.)



TSMC, IEDM'14



Panasonic, ISPSD'15

# Other dynamic behavior?

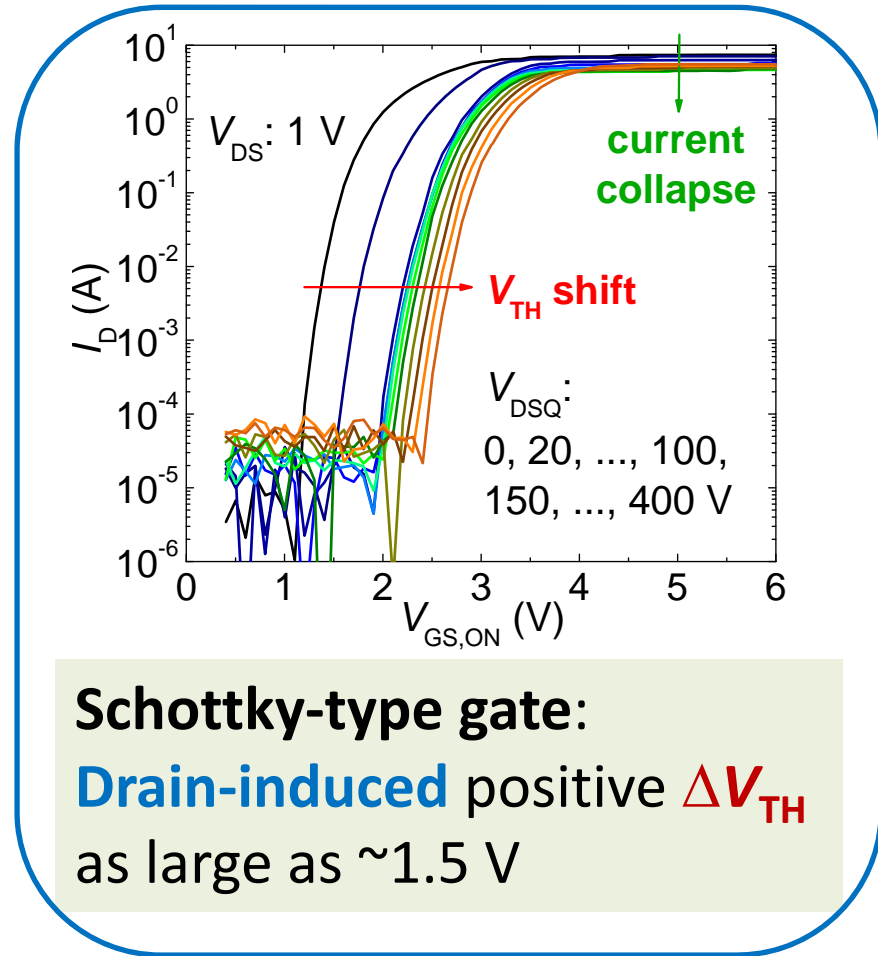
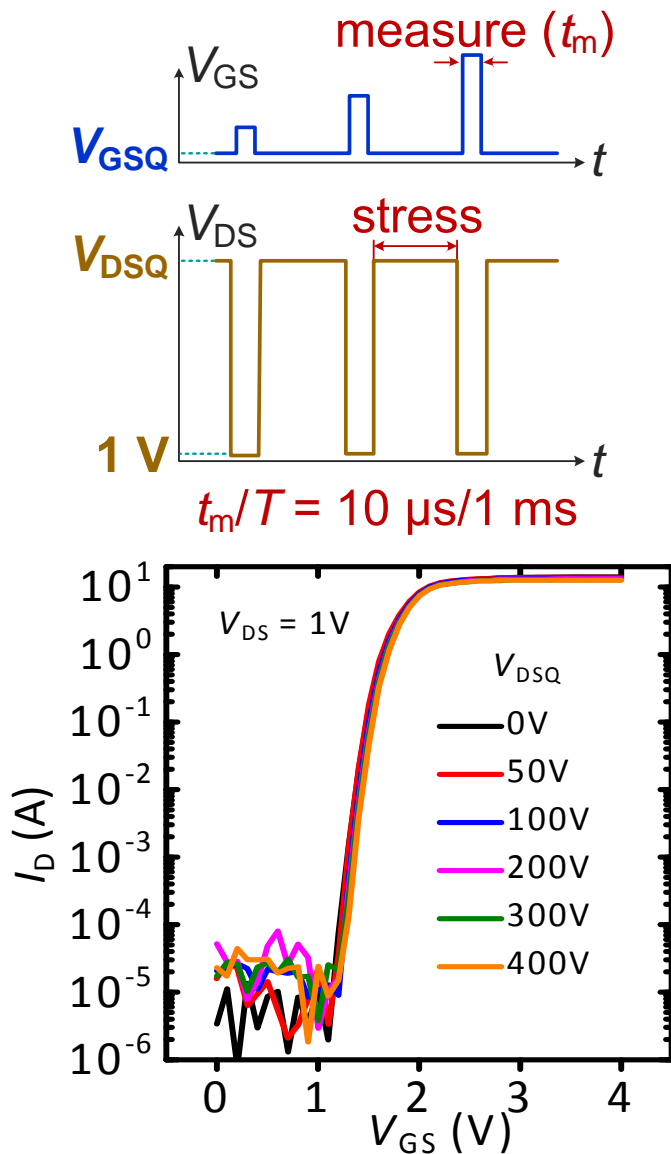
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*Equally important (if not more) but less studied*

- **Dynamic  $V_{TH}$  and impact to:**
  - gate driver design (e.g. how much overdrive is sufficient?)
  - transient behavior/performance evaluation
- **Dynamic  $I_{OFF}$  and impact to:**
  - OFF-state power consumption evaluation
  - choice of *gate turn-off voltage*

# Dynamic $V_{TH}$ in E-mode $p$ -GaN HEMT

Pulsed transfer curve measurement:



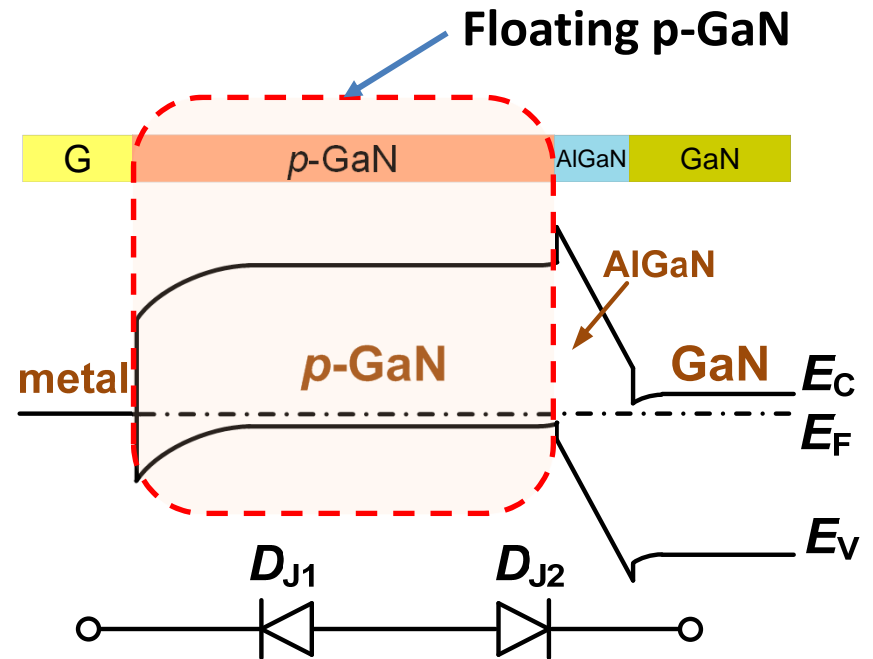
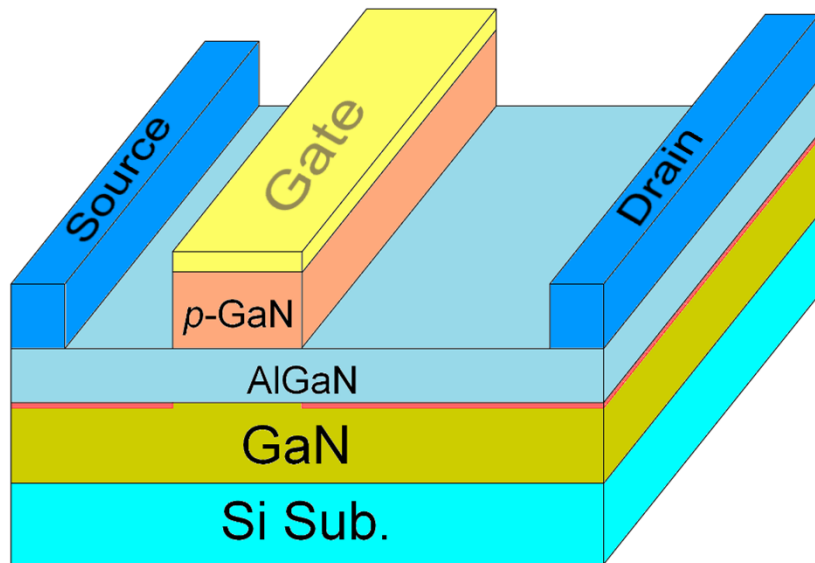
**Schottky-type gate:**  
**Drain-induced** positive  $\Delta V_{TH}$   
 as large as  $\sim 1.5 V$

**Ohmic-type gate, e.g. GIT:**  
 Stable  $V_{TH}$  with small  $\Delta V_{TH}$



# Dynamic $V_{TH}$ in Schottky p-GaN HEMT

Root cause: the floating p-GaN

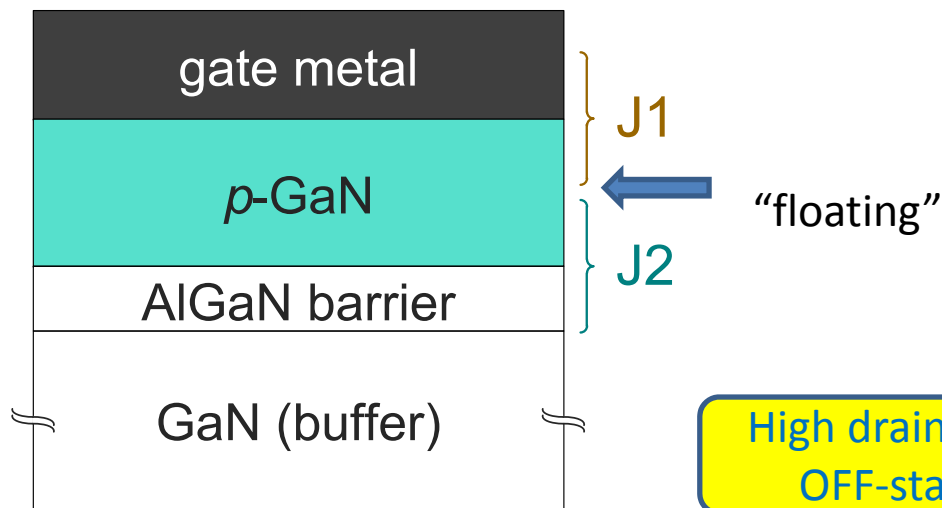


- Model: Schottky junction ( $D_{J1}$ ) + p-i-n heterojunction ( $D_{J2}$ )
- Charge storage/emission in the floating p-GaN  $\rightarrow V_{TH}$  instability

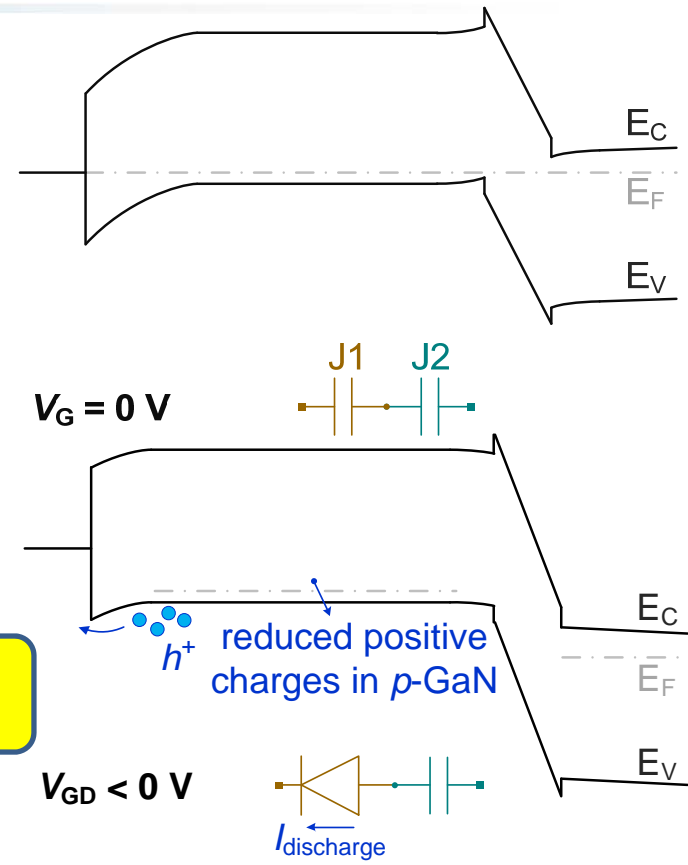
Dynamic  $V_{TH}$

# Mechanism of the drain induced $\Delta V_{TH}$

J1 & J2: back-to-back  
 $p$ -GaN: floating



High drain bias  
 OFF-state

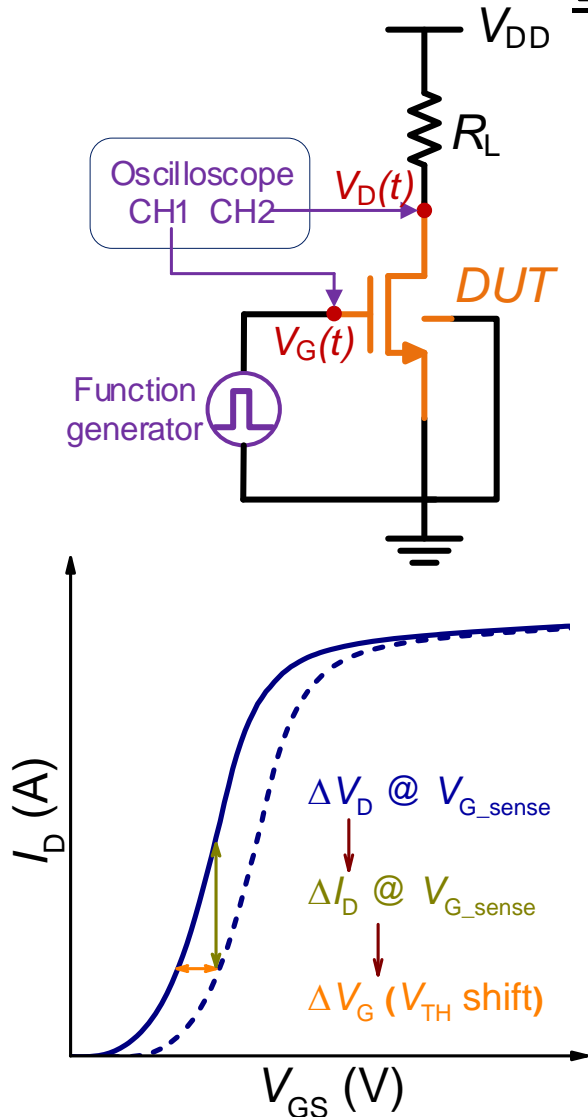


**Stress:**  $V_{GD} < 0$ , J1 forward-biased,  $h^+$  emission from  $p$ -GaN to metal  
**Measure:** reduced positive charges cannot be recovered immediately.

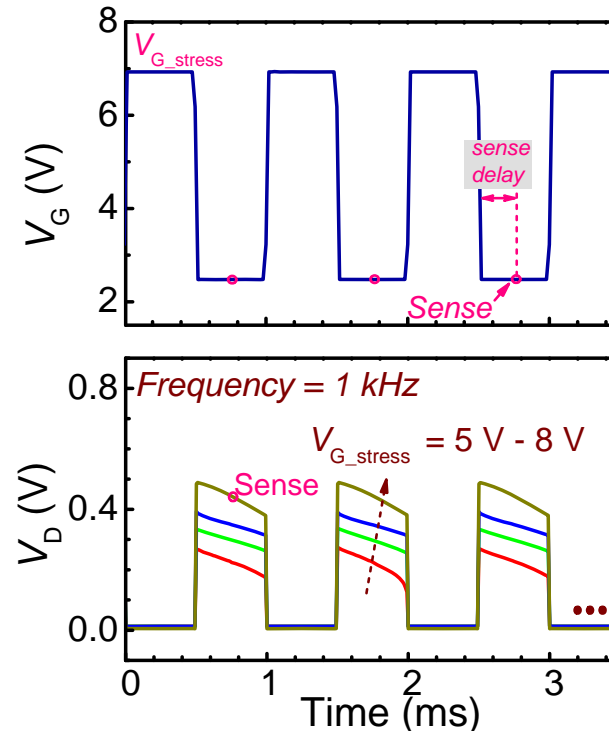
Hanxing Wang, et al., "Maximizing the Performance of 650-V  $p$ -GaN Gate HEMTs: Dynamic  $R_{ON}$  Degradation and Circuit Design Considerations," *IEEE Trans. Power Electronics*, July, 2017

# Gate induced $\Delta V_{TH}$

## Dynamic gate stress



$$I_D = \frac{V_{DD} - V_{DS}(t)}{R_L}$$

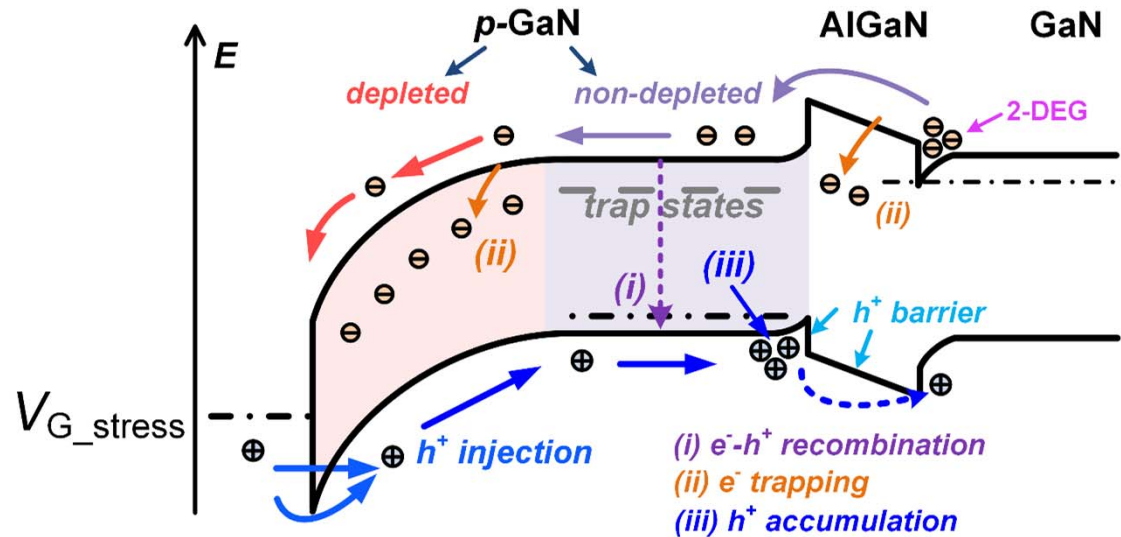
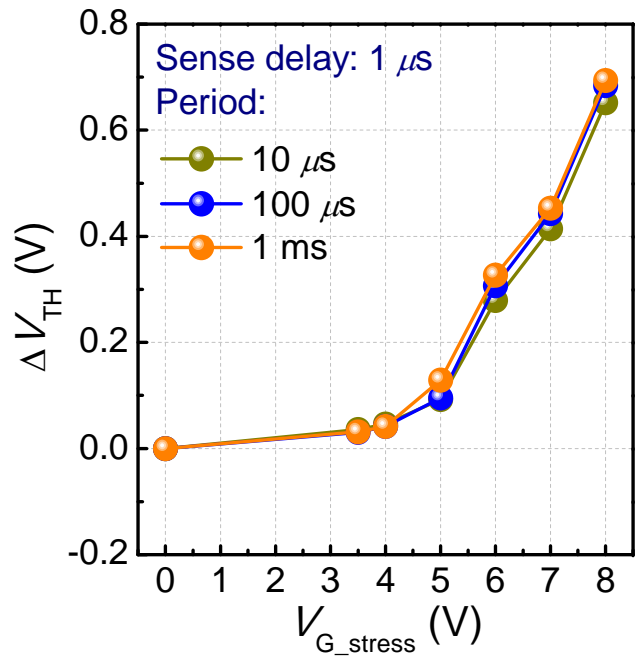


- Dynamic  $V_{TH}$  is extracted from  $V_D(t)$ .

# Gate induced positive $\Delta V_{TH}$

Positive  $V_{TH}$  shift after gate turn-on

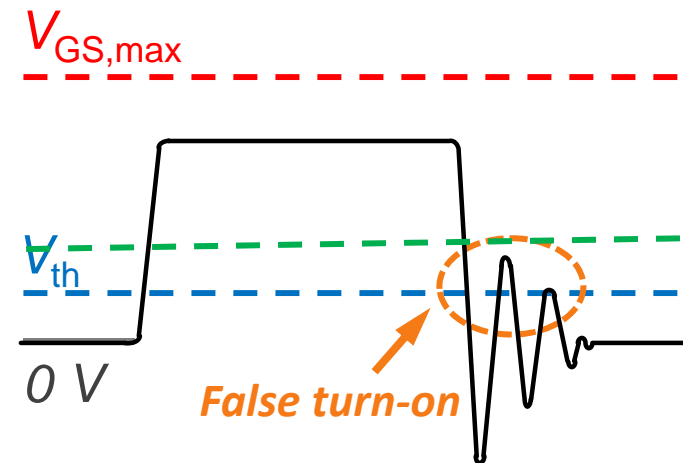
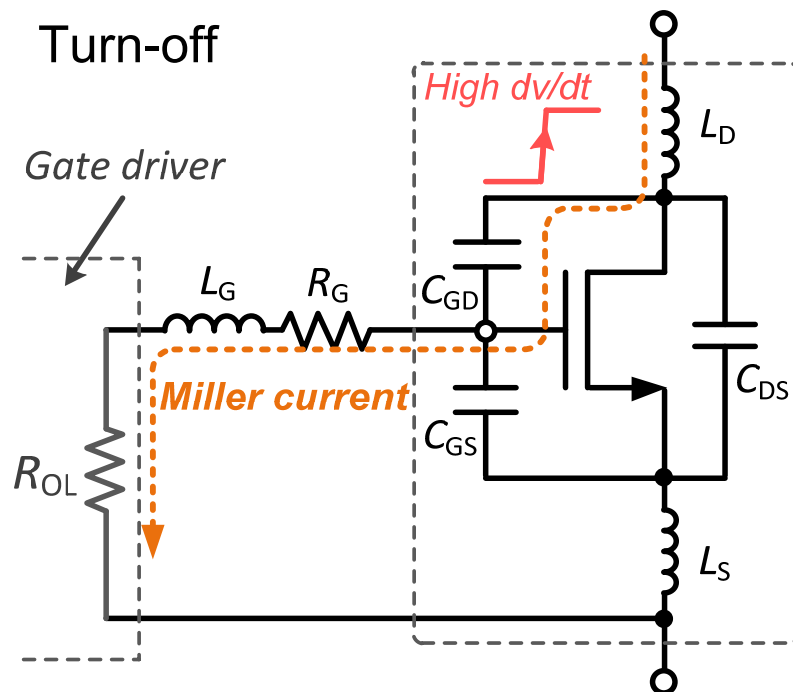
Mechanism: electron trapping in the depleted region of the  $p$ -GaN layer



*J. He, T. Gao and K. J. Chen, IEEE Electron Device Lett., p. 1576, Oct. 2018.*

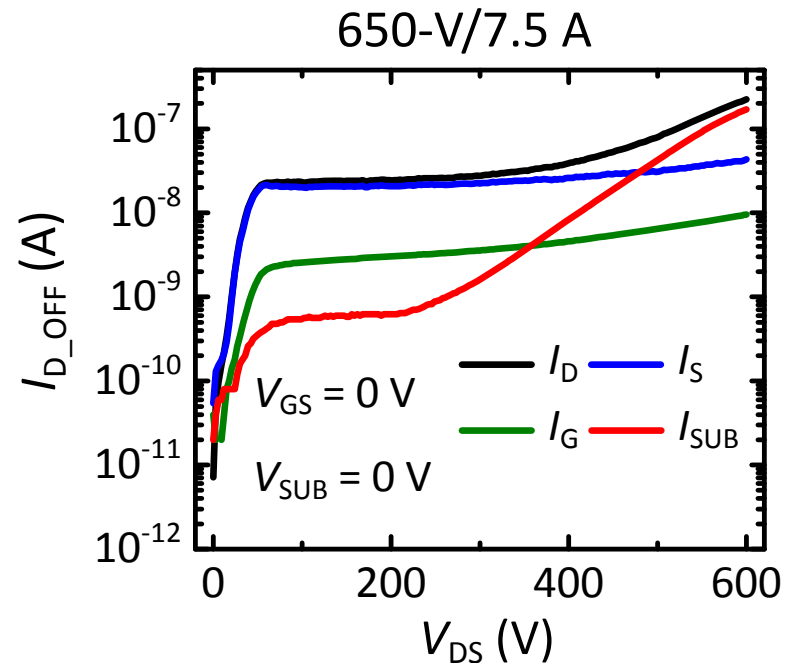
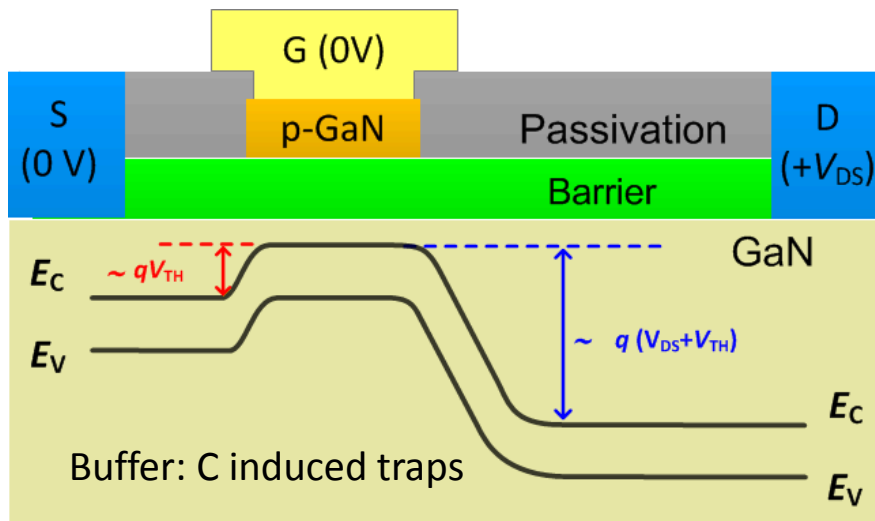
# Impact of $V_{TH}$ shift

- **Drain induced positive  $\Delta V_{TH}$**   $\rightarrow$  more positive  $V_G$  (i.e. gate overdrive) to turn on the switch and narrower  $V_{G,ON}$  range
- **Gate induced positive  $\Delta V_{TH}$**   $\rightarrow$  raised  $V_{TH}$  at OFF state  $\rightarrow$  enhanced false turn-on immunity



# OFF-state leakage current

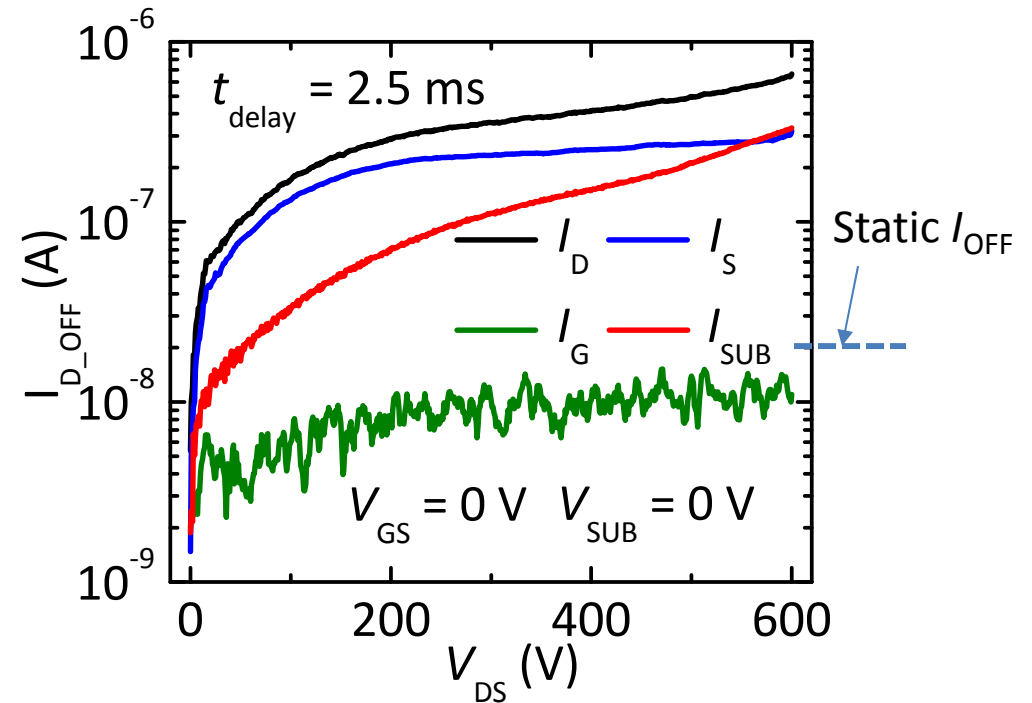
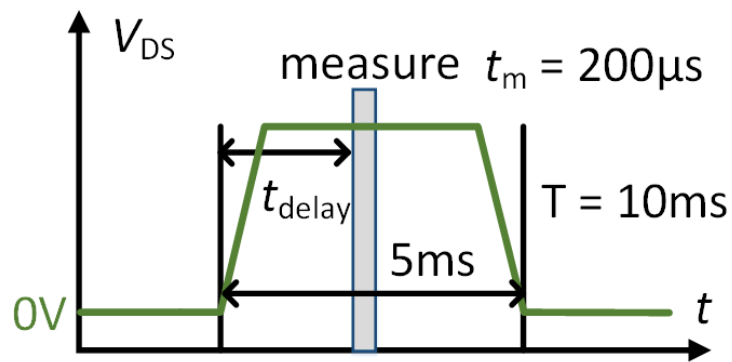
- No  $p-n$  junctions between source and drain in the leakage path (e.g. buffer layer)
- Low leakage current is attributed to the buffer with raised energy band -- a result of C-doping.



Quasi-static  $I_{OFF}$

# Dynamic $I_{\text{OFF}}$

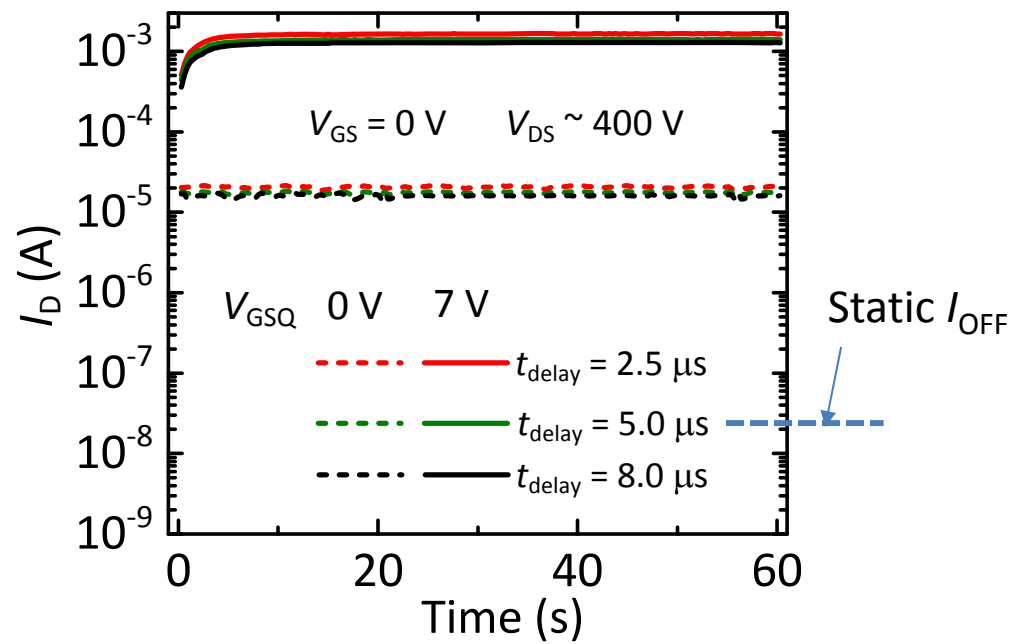
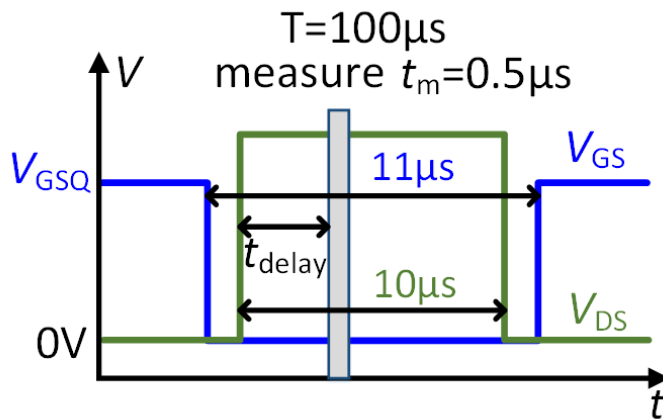
## Slow dynamic measurement



- Reduced voltage blocking capability in the buffer (both lateral and vertical)
- Reduced energy barrier due to unfilled electron traps in the buffer

# Dynamic $I_{OFF}$ under fast switching

fast dynamic measurement



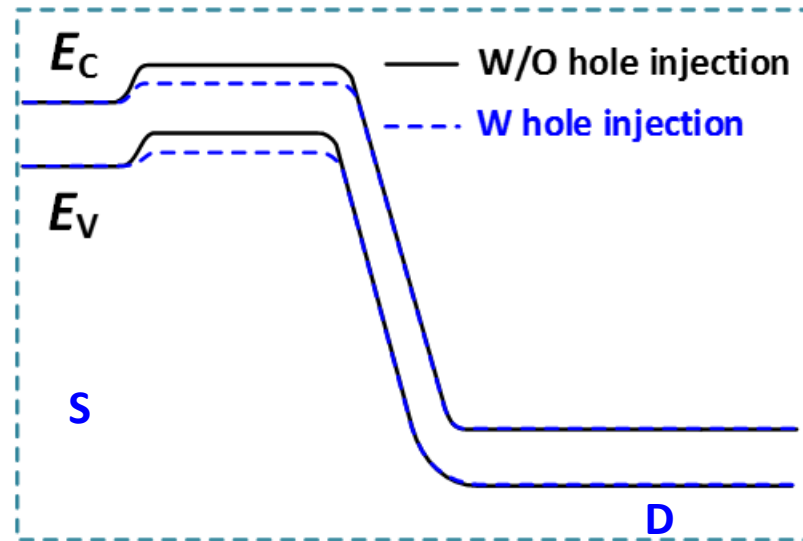
Dynamic  $I_{OFF}$  vs. Static  $I_{OFF}$

- 1000 x increase without turning on the switch
- $10^5$  x increase after  $V_{G,ON} = 7$  V  $\rightarrow$  induced by hole injection into the buffer

OFF-state power loss is  $\sim 10\%$  of the ON-state conduction loss.



# Dynamic $I_{OFF}$ increase from hole injection

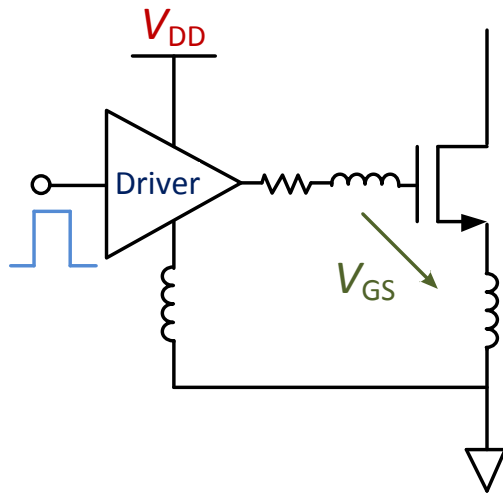


Hole injection into the buffer  $\rightarrow$  lower barrier

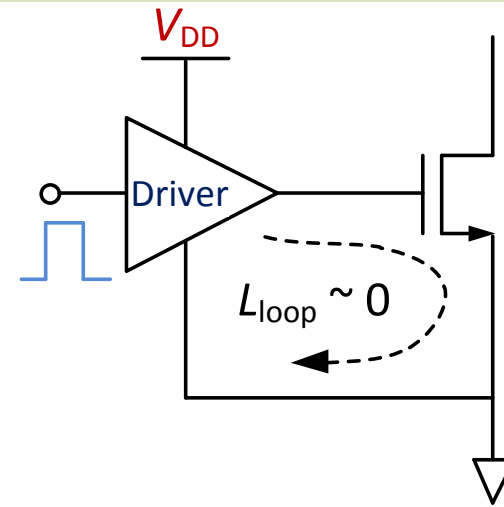
# Critical gate drive margin

- Lower threshold voltage  $V_{th}$   $\Rightarrow$  False turn-on (miller effect)
- Narrower gate drive voltage  $V_{GS,ON}$   $\Rightarrow$  Lower noise immunity (gate ringing)

## Suppression of parasitic inductance by integration

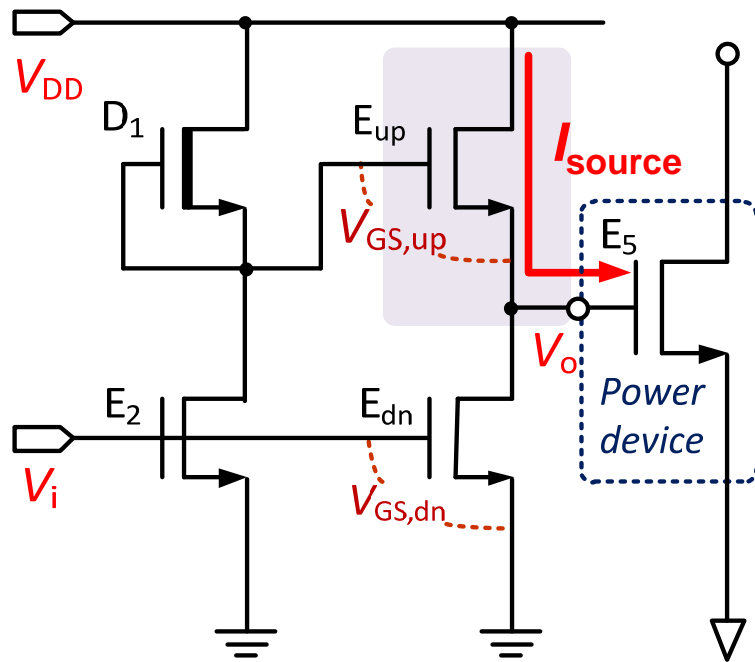


*Si driver + GaN switch*



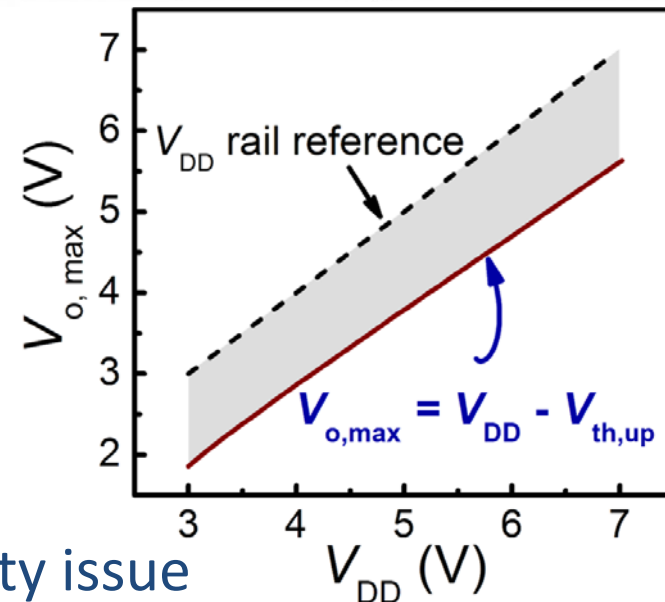
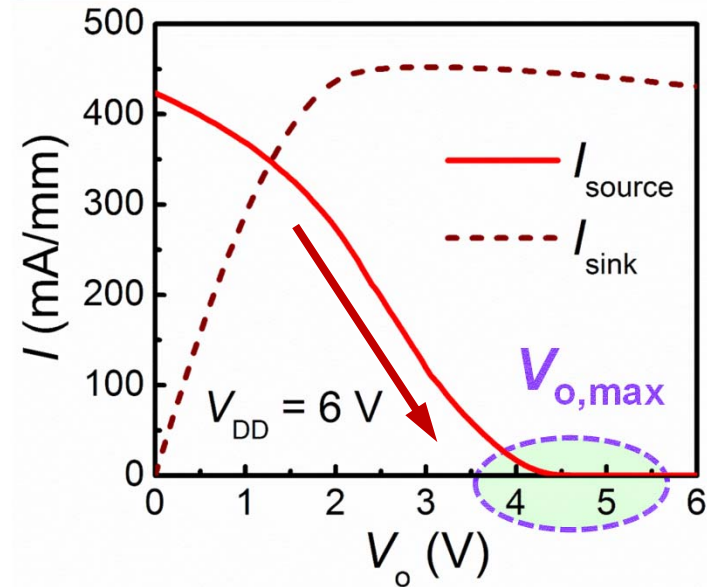
*GaN driver + GaN switch*

# Gen-I integrated gate drive: issues

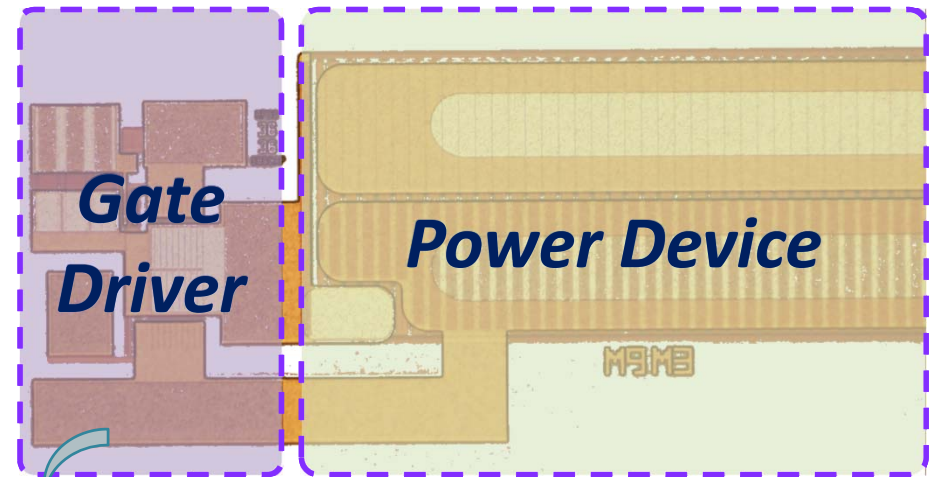
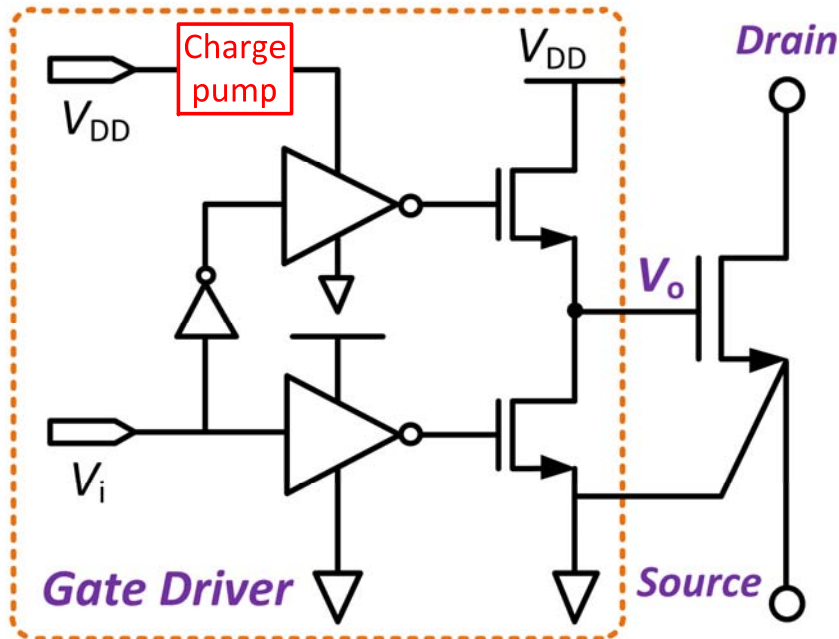


During the charging process:

- Charging current reduction
- $V_{o, max} = V_{DD} - V_{th,up}$
- Larger  $V_{DD}$  ( $> 7.5$  V)  
 $\rightarrow$  exceeding  $V_{G,max}$   $\rightarrow$  gate reliability issue



# Gen-II gate drive scheme

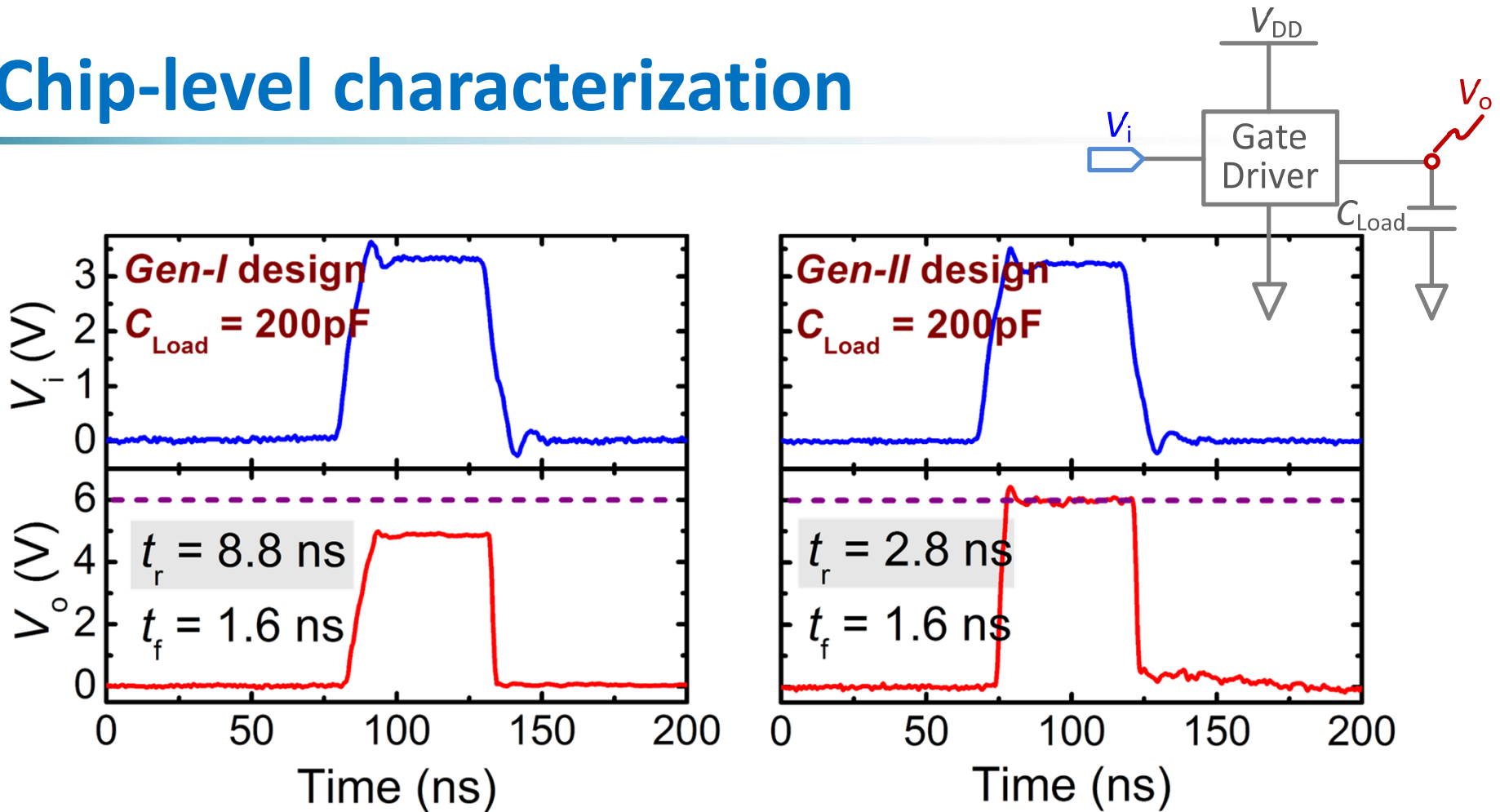


**15% size including bonding pads**

*Novel gate driver design (Gen-II)*

- Charge pump unit → Help maintain the charging current
- Chip size: 4.6 mm × 1.1 mm (~5 mm<sup>2</sup> including 130-mΩ switch)

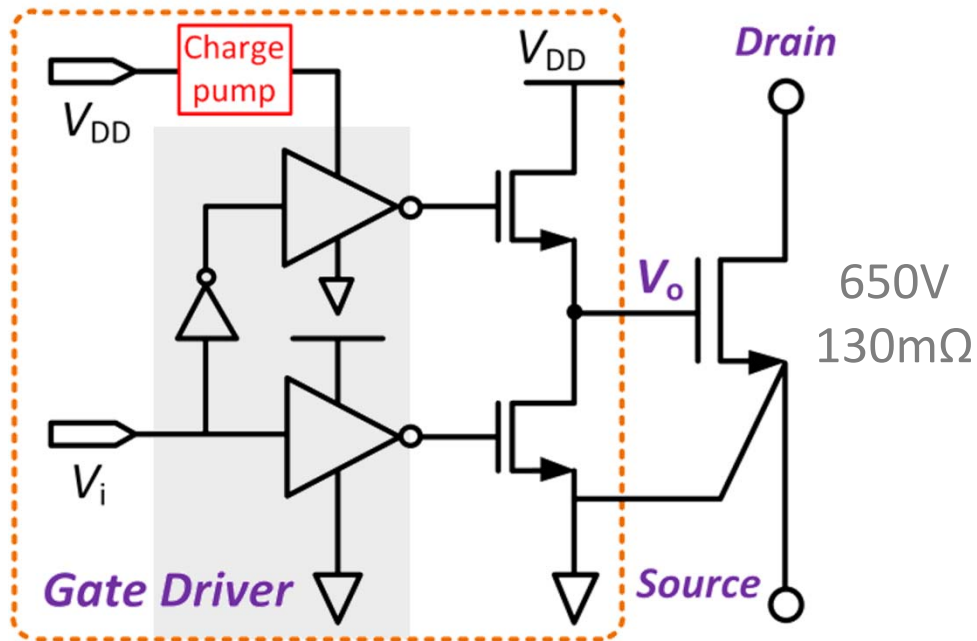
# Chip-level characterization



## Driving capability

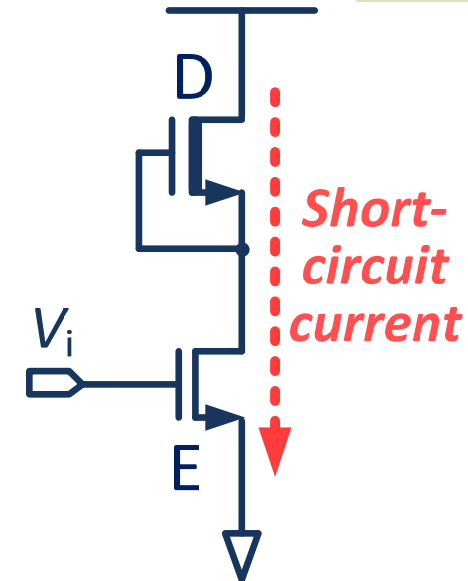
The *Gen-II* gate driver can provide with both enhanced driving capability (3X) and rail-to-rail output ( $V_{o,max} = V_{DD}$ ).

# Power consumption



DCFL circuit

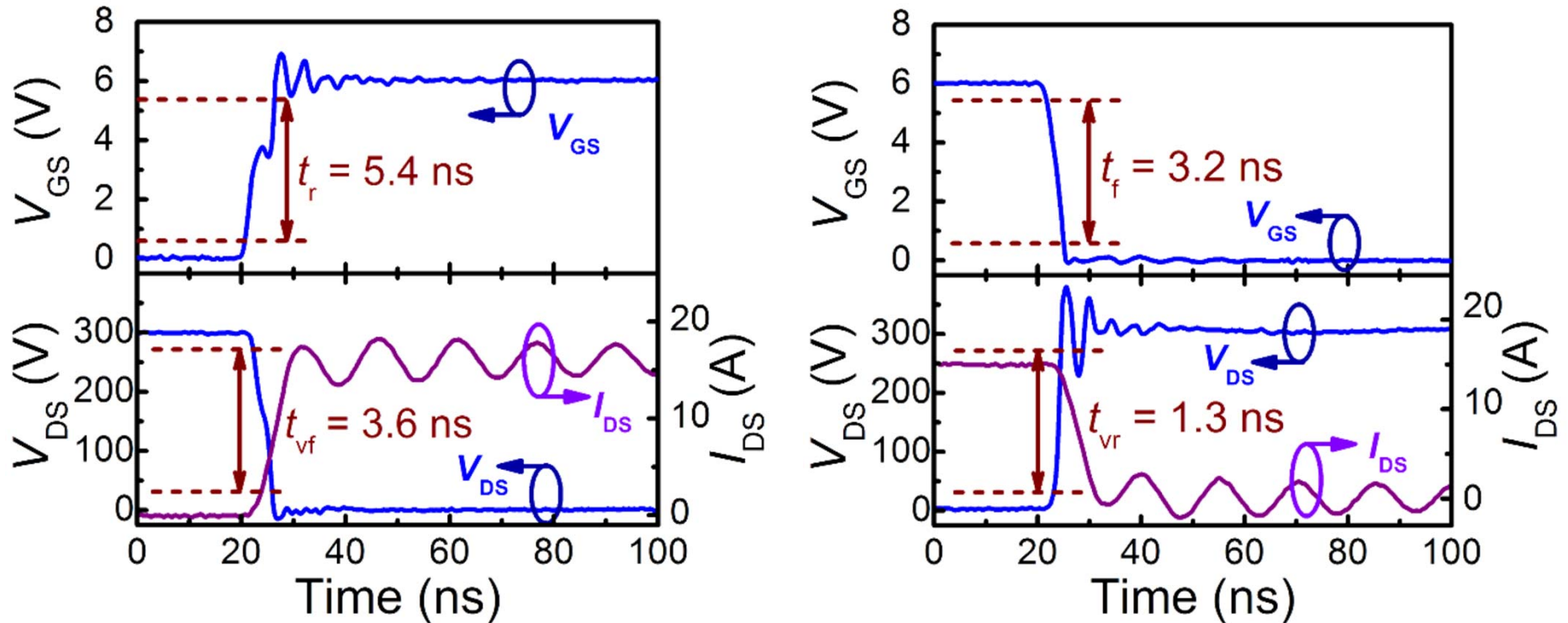
Logic stage



*Power consumption (from integrated gate driver)*

- Caused by the DCFL (direct coupled FET logic) circuits (**not CMOS**)
- Standby power consumption ( $I_{DD} \sim 6 \text{ mA @ } V_{DD} = 6 \text{ V}$ )

# Switching performance using a double-pulse tester



- Small ringing & suppressed false turn-on
- Without the need of negative  $V_{GS}$
- Minimum turn-off time: 1.3 ns ( $dv/dt_{(max)} = 336$  V/ns)

# Summary

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- ❑ In addition to dynamic  $R_{ON}$ , the deployment of GaN-on-Si power devices is also affected by other critical dynamic characteristics including
  - Dynamic  $V_{TH}$  : impact on gate overdrive  $V_{G,ON}$
  - Dynamic  $I_{OFF}$  : impact on OFF-state power consumption
  
- ❑ Monolithically integrated gate driver leads to reduced parasitic inductance and offers several benefits including
  - Higher switching speed
  - Higher tolerance of tight gate driving voltage range



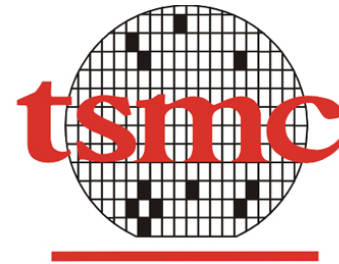
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# Thank you!

## Acknowledgement

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- TSMC



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